

U.S. Department of Commerce Patent and Trademark Office Atty. Docket No. | Serial No. | 27391/US588 | 10/617,560 | Applicant | Nakayama

## INFORMATION DISCLOSURE STATEMENT

7/11/03		Group .	
CUMENT	S		
Name	Class	Subclass	Filing Date if

		U.S. PA	TENT DOCU	MENTS			
*Examiner Initials	Document Number	Issue Date	Name		Class	Subclass	Filing Date if Appropriate
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K.S. IMM	1109
*EXAMINER: Initial if reference considered, whether or not citation is in con-	